

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Akihiko OTOGURO, et al.**

Serial Number: **Not Yet Assigned**

Filed: **June 25, 2003**

For: **METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE AND METHOD
OF FORMING PATTERN**

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

June 25, 2003

Sir:

In compliance with 37 CFR 1.56, Applicants call to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449.

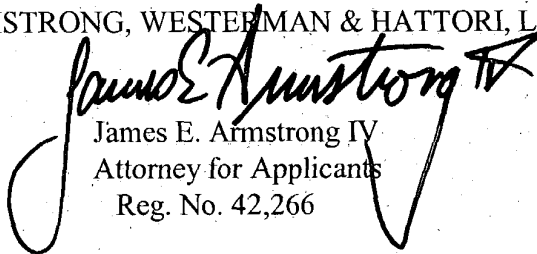
A copy of each of the references are enclosed herewith.

In the event there are any fees due in connection with the filing of this paper, please charge

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Respectfully submitted,

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PATENT TRADEMARK OFFICE

Enclosures: PTO-1449; References (4)

INFORMATION DISCLOSURE STATEMENT PTO-1449	Atty. Docket No. 030757	Serial No. New Application
	Applicant(s): Akihiko OTOGURO, et al.	
	Filing Date: June 25, 2003	Group Art Unit: Not Yet Assigned

U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
_____	AA					
_____	AB					
_____	AC					
_____	AD					

FOREIGN PATENT DOCUMENTS

	Document No.	Date	Country	Translation (Yes or No)	
_____	AE	4-5658	01/09/92	Japan	Yes-Abstract/Discussed in the specification
_____	AF	60-254034	12/14/85	Japan	Yes-Abstract/Discussed in the specification
_____	AG	5-265224	10/15/93	Japan	Yes-Abstract/Discussed in the specification
_____	AH				
_____	AI				

OTHER DOCUMENTS

_____	AJ	J.M. Moran et al.; "High resolution, steep profile resist patterns"; <i>Journal of Vacuum Science Technology</i> ; Vol. 16; No. 6; November/December 1979; pp. 1620-1624./Discussed in the specification.
_____	AK	
Examiner		Date Considered